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PATENT
ATTORNEY DOCKET: 46884-5345

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Satoshi MATSUMOTO et al.) Confirmation No.: 8192
Application No.: 10/518,392) Group Art Unit: 2859
Filed: July 25, 2005) Examiner: Gail Kaplan Verbitsky
For: LASER PROCESSING APPARATUS,)
LASER PROCESSING)
TEMPERATURE MEASURING)
APPARATUS, LASER PROCESSING)
METHOD, AND LASER PROCESSING))
TEMPERATURE MEASURING)
METHOD)

Commission for Patents
U.S. Patent and Trademark Office
Customer Window, Mail Stop Amendment
Alexandria, VA 22314

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In an Office Action dated March 8, 2007, the period for response to which extends through April 9, 2007 (April 8 being a Sunday), the Examiner required restriction/election under 35 U.S.C. § 121 between Group I, (claims 1-7) allegedly drawn to “laser processing apparatus and method” or Group II (claims 8-15), allegedly drawn to “laser processing apparatus and method for welding resins members.”

Applicants hereby elect Group II (claims 8-15) for examination.

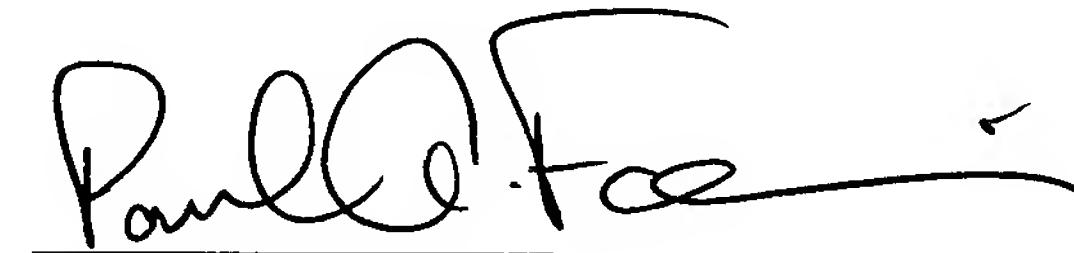
Applicants respectfully request formal examination of this application.

Applicants respectfully assert that no additional fee is due in connection with the filing of this response. However, if there are any additional fees due in connection with the filing of this response, please charge those fees to Deposit Account No. 50-0573.

Respectfully submitted,

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By:



Paul A. Fournier

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Dated: April 9, 2007

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